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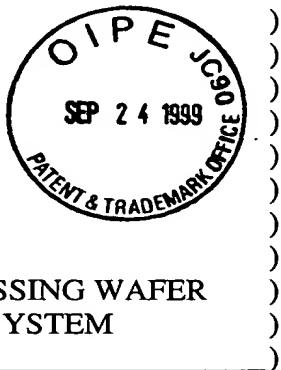
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Svirchevski et al.

Application No: 09/336,401

Filed: June 18, 1999

For: POST-PLASMA PROCESSING WAFER
CLEANING METHOD AND SYSTEM

Group Art Unit: 1765

Examiner: Unassigned

Atty. Docket No: LAM1P109

Date: September 20, 1999

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, DC 20231 on September 20, 1999.

Signed: 

Kay Harlow

**INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR §§1.56 AND 1.97(c)**

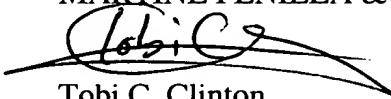
Assistant Commissioner for Patents
Box: IDS
Washington, DC 20231

Dear Sir:

The reference listed in the attached PTO Form 1449, a copy of which is attached, may be material to examination of the above-identified patent application. Applicants submit this reference in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make this reference of official record in this application.

This Information Disclosure Statement is believed to be filed before the mailing date of a first Office Action on the merits. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 50-0805 (Order No. LAM1P109).

Respectfully submitted,
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